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APPLICANTS

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** CONTINUING DATA *****

This application is a 371 of PCT/JP04/00370 01/19/2004 MDW 9/9/05

** FOREIGN APPLICATIONS *****

JAPAN 2003-016659 06/24/2003 MDW 9/9/05

Foreign Priority claimed <input checked="" type="checkbox"/> yes <input type="checkbox"/> no	35 USC 119 (a-d) conditions <input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after met	STATE OR COUNTRY JAPAN	SHEETS DRAWING 4	TOTAL CLAIMS 15	INDEPENDENT CLAIMS 2
Verifier and Acknowledged <i>Monica D. Palmer MDW</i> Examiner's Signature	Allowance Initials				

ADDRESS

22850

TITLE

Method of cvd for forming silicon nitride film on substrate

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